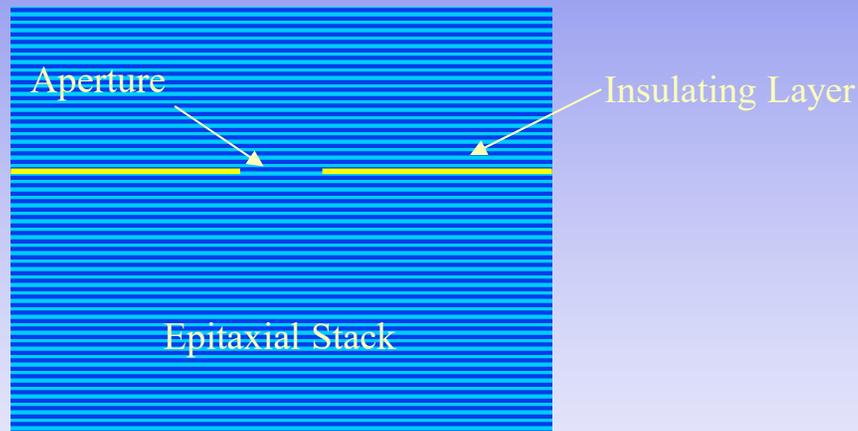


Lateral Wet Oxidation

Forms an insulating layer or an aperture in an epitaxial stack.
Oxidation starts from the edge of the stack and penetrates inward.



The layer that forms the aperture is typically AlGaAs with a high aluminum mole fraction.

Lateral Wet Oxidation of AlGaAs

- Works best in a high Al content $\text{Al}_x\text{Ga}_{1-x}\text{As}$ layer.
 - Where $x > 0.95$
- Wet oxidation temperature of 350°C to 450°C is needed.
 - In the absence of oxygen
 - In carrier gas with water vapor
- Oxidized layer is composed mostly of Al_2O_3
 - As_2O_3 should diffuse out of the layer
 - Ga_2O_3 Stays

Common Knowledge

- Dry oxidation by O_2 forms dense $\alpha-Al_2O_3$ on the surface that is a barrier to further oxidation.
- Wet oxidation by moisture forms porous $\gamma-Al_2O_3$ that continues to oxidize.
- Oxidation needs to be performed in the absence of O_2 .
- Volatile As_2O_3 diffuses out of the layers.

Chemistry

Reaction of Aluminum with Water



From room temperature to 280°C, Al(OH)₃ is most favored.

From 280 - 480°C, AlO(OH) is most favored (diaspore).

Above 480°C, Al₂O₃ is the most favored product.

- As₂O₃ melts at 315°C and boils at 465°C
- It is soluble in water at 20 g/L (25 °C)

Experimental Observations

- An amorphous hydroxide region forms at the oxidation front first and visibly transforms to porous γ -alumina.
- A vertical contraction of 6% to 7% is observed when layers of 97% to 98% AlGaAs oxidize.
- Stress is reduced with dry annealing that allows byproducts to escape.
- Oxidation can leak into an adjacent high aluminum content layer, forming a wanted or unwanted tapered tip.